

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventors: Pablo I. Rovira
Assignee: Nanometrics Incorporated
Title: Optical Metrology System with Combined Interferometer and Ellipsometer
Serial No.: 10/016,943 Filing Date: December 13, 2001
Examiner: Samual A. Turner Group Art Unit: 2877
Docket No.: NAN051 US Confirmation No.: 7400

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Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Santa Clara, California
October 31, 2003

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TECHNOLOGY CENTER 2800

RESPONSE TO OFFICE ACTION

Dear Sir:

This Response to Office Action is responsive to the August 20, 2003, Office Action, which has a statutorily shortened period for response that ends November 20, 2003. Please enter the following amendments before taking action on the merits of the above-referenced application.

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